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Docket No. EATNP152US

03-IMP-025

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In **PATENT** application of:

Applicant: Peter L. Kellerman et al.
Application No.: 10/695,153
For: METHOD OF MAKING A MEMS ELECTROSTATIC CHUCK
Filing Date: October 28, 2003
Examiner: Trung Q. Dang
Art Unit: 2823

REPLY TO OFFICE ACTION DATED FEBRUARY 10, 2005

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Favorable reconsideration of the above-identified application is respectfully requested in view of the following remarks.